

**Notice of References Cited**Application/Control No.  
10/056,017Applicant(s)/Patent Under  
Reexamination  
NOVAK ET AL.Examiner  
Zia R. HashmiArt Unit  
2881

Page 1 of 1

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*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
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\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
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